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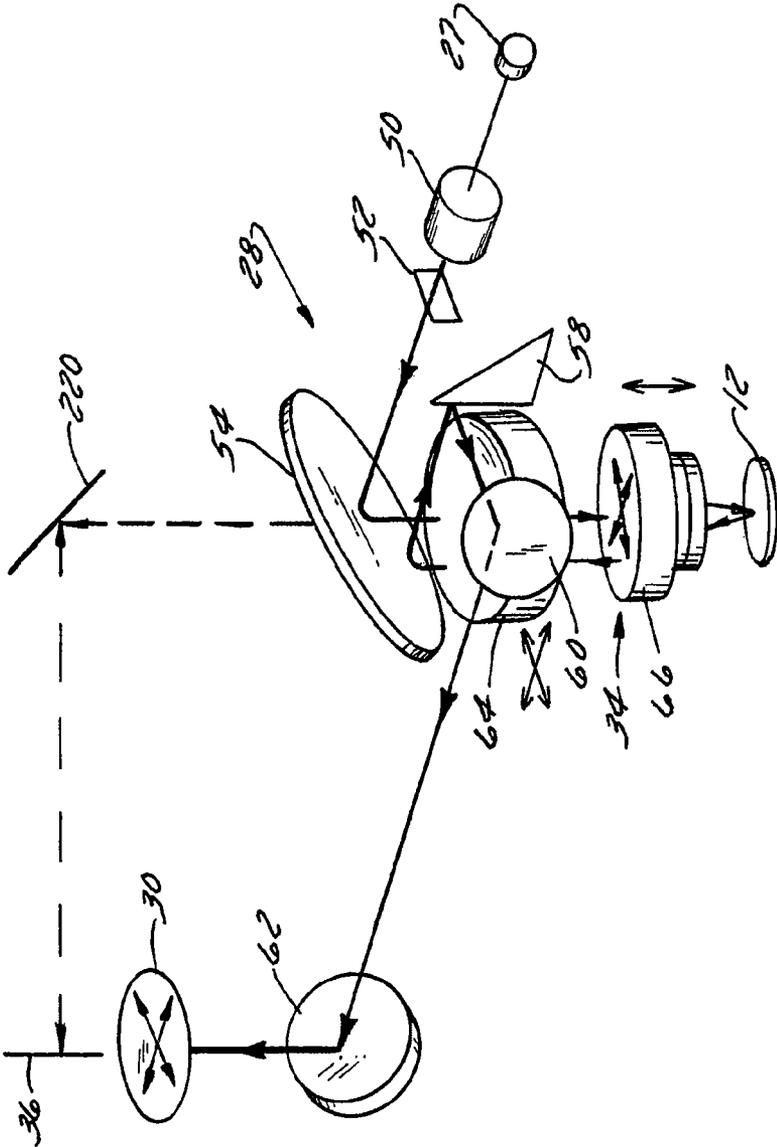


FIG. 2

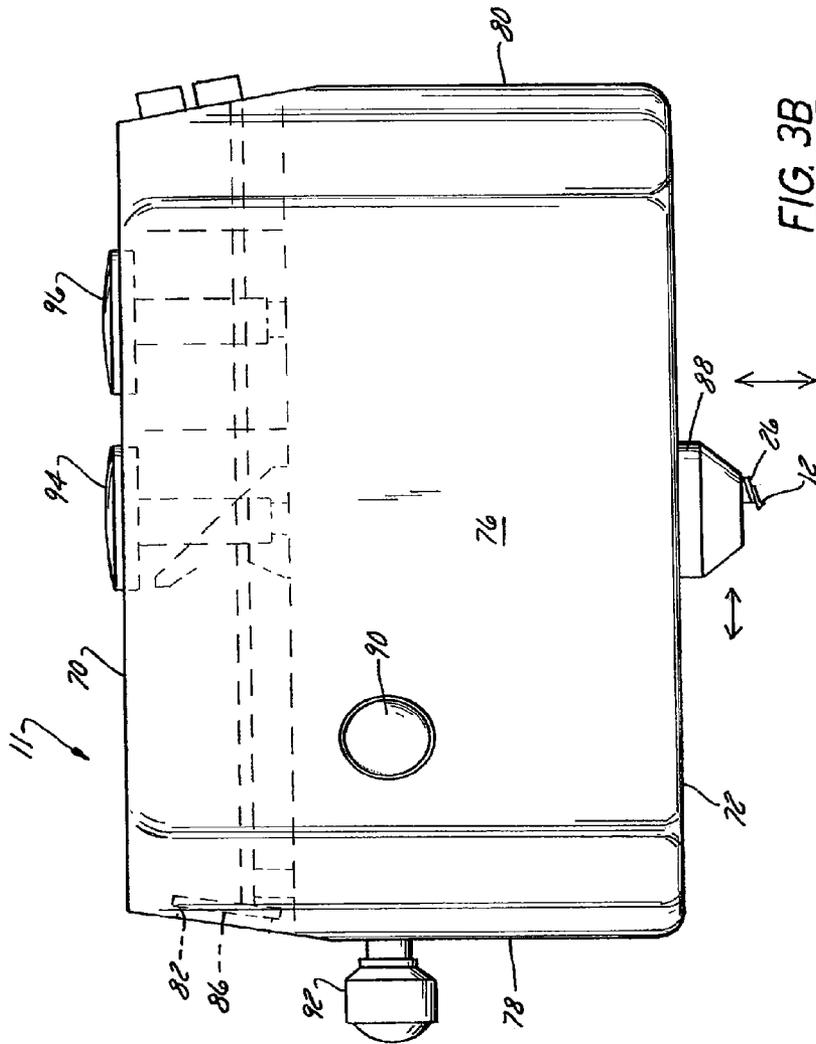


FIG. 3B

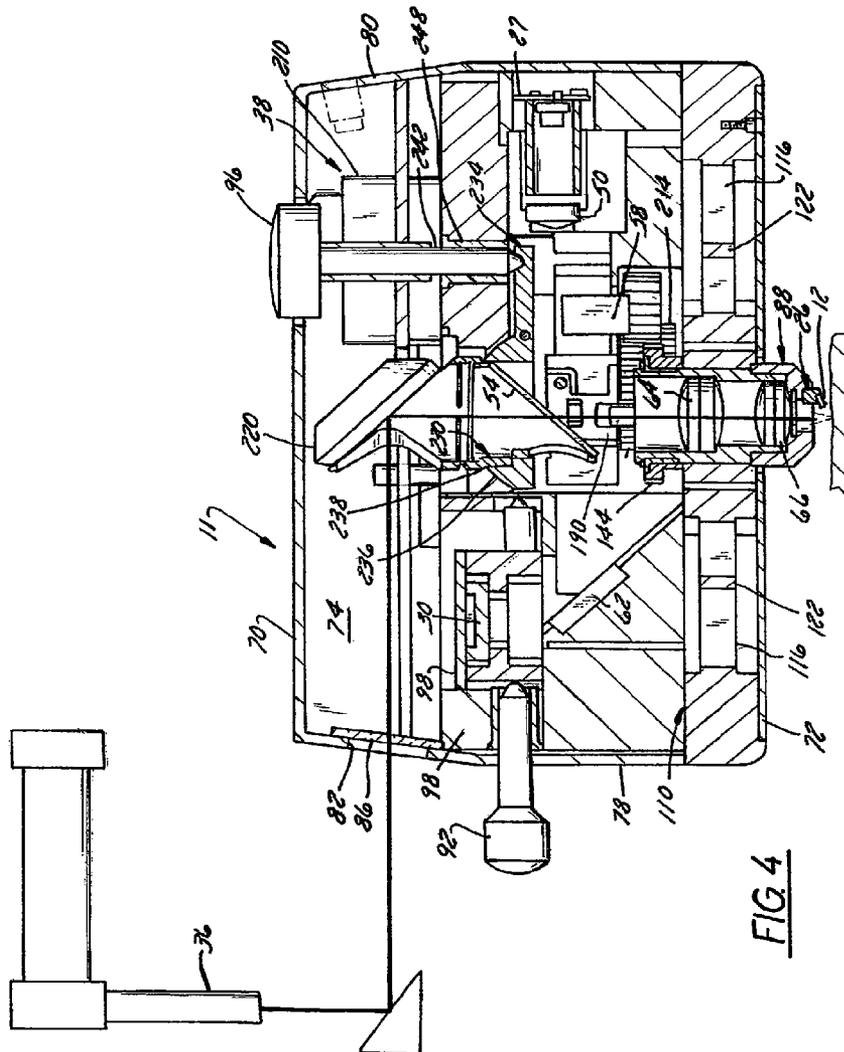


FIG 4

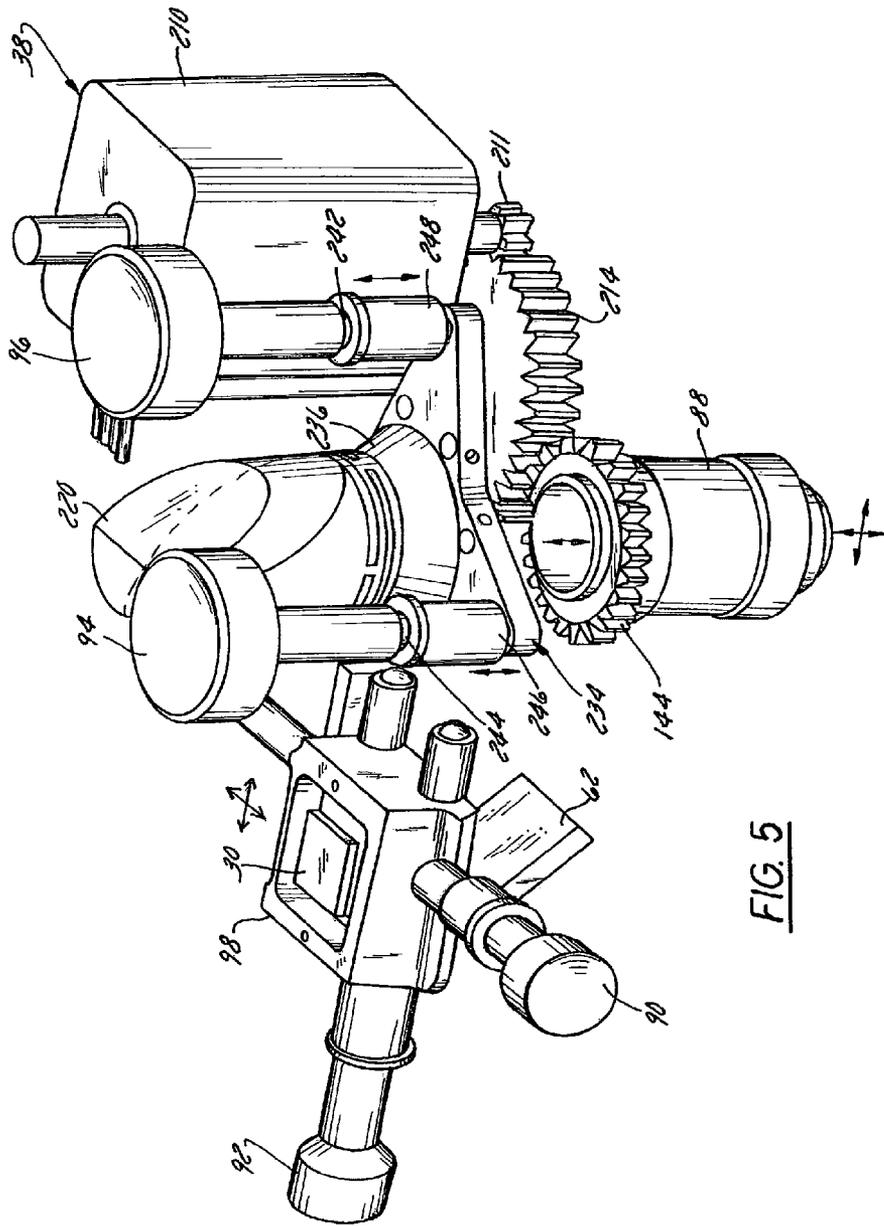


FIG. 5

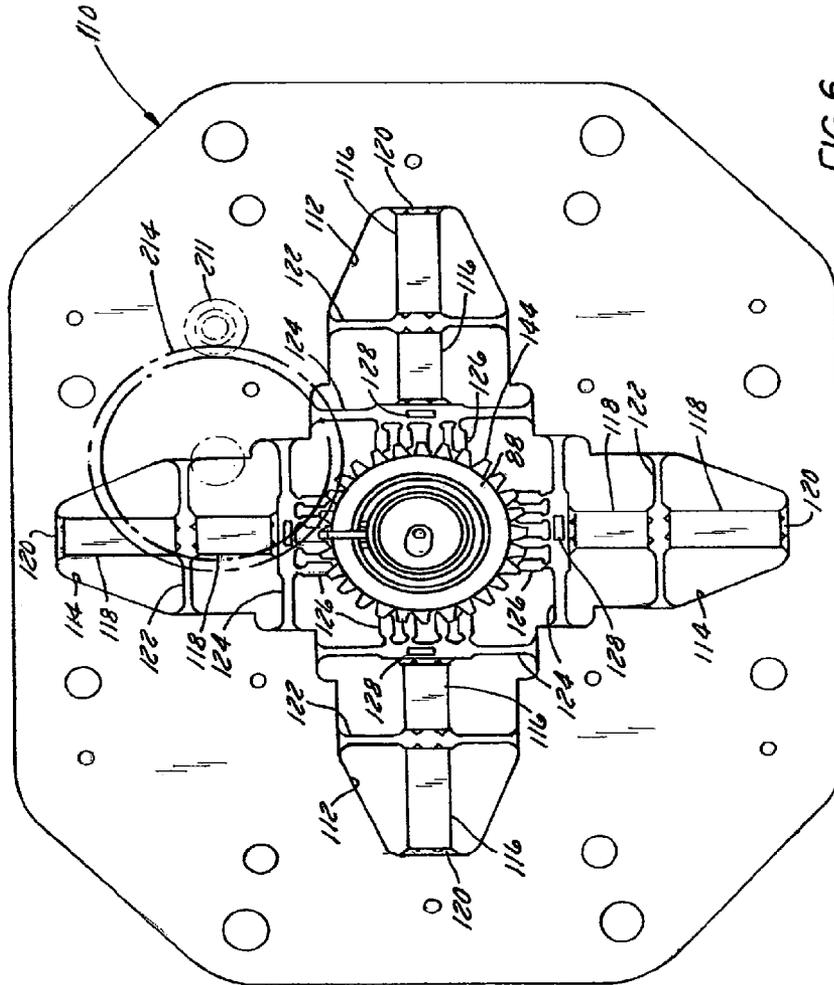


FIG. 6

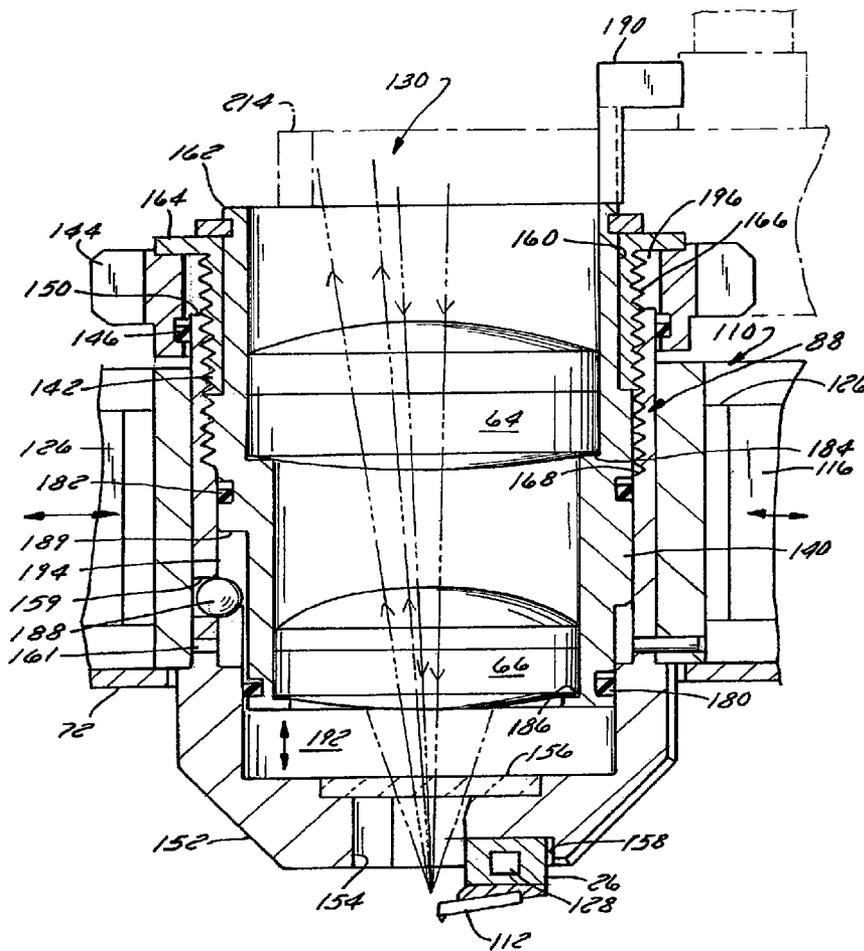


FIG. 7A

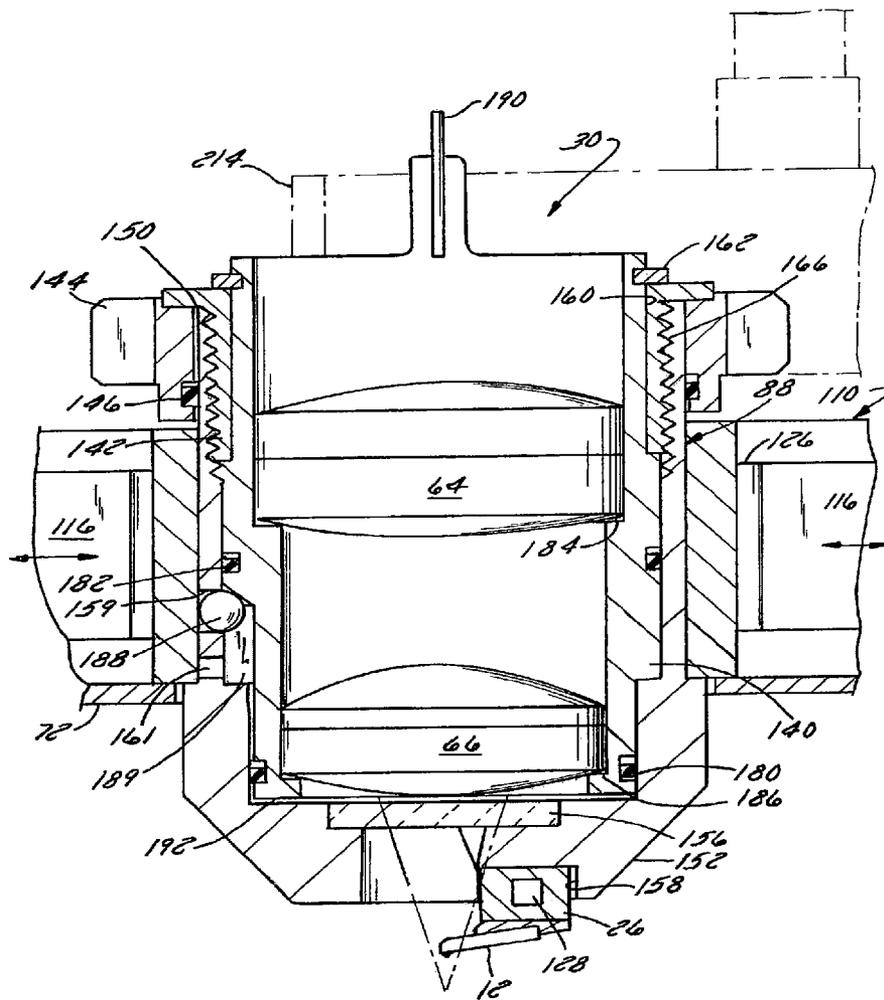


FIG. 7B

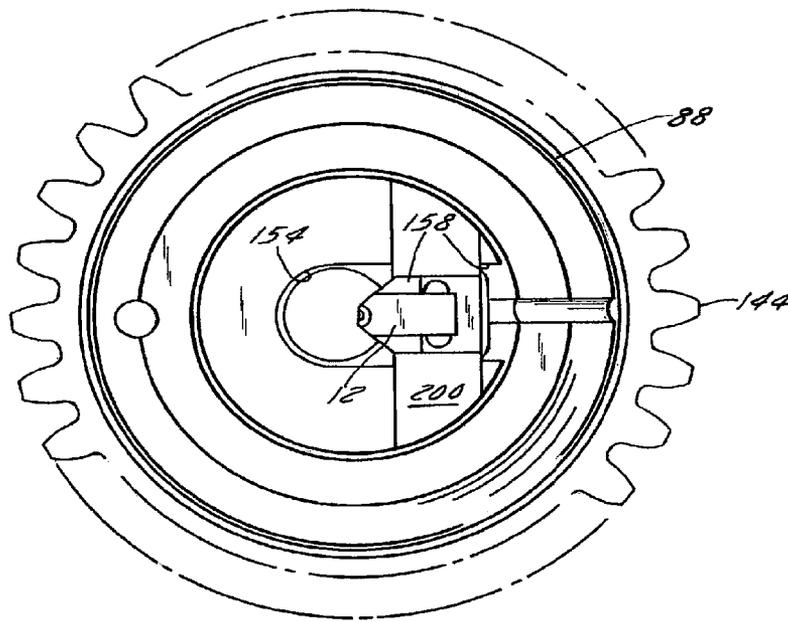


FIG. 8

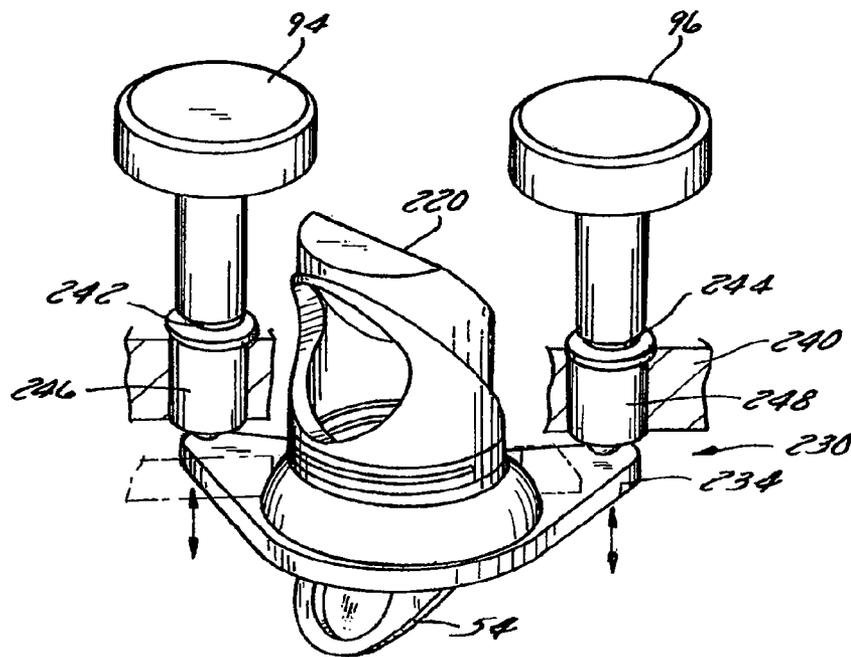


FIG. 9

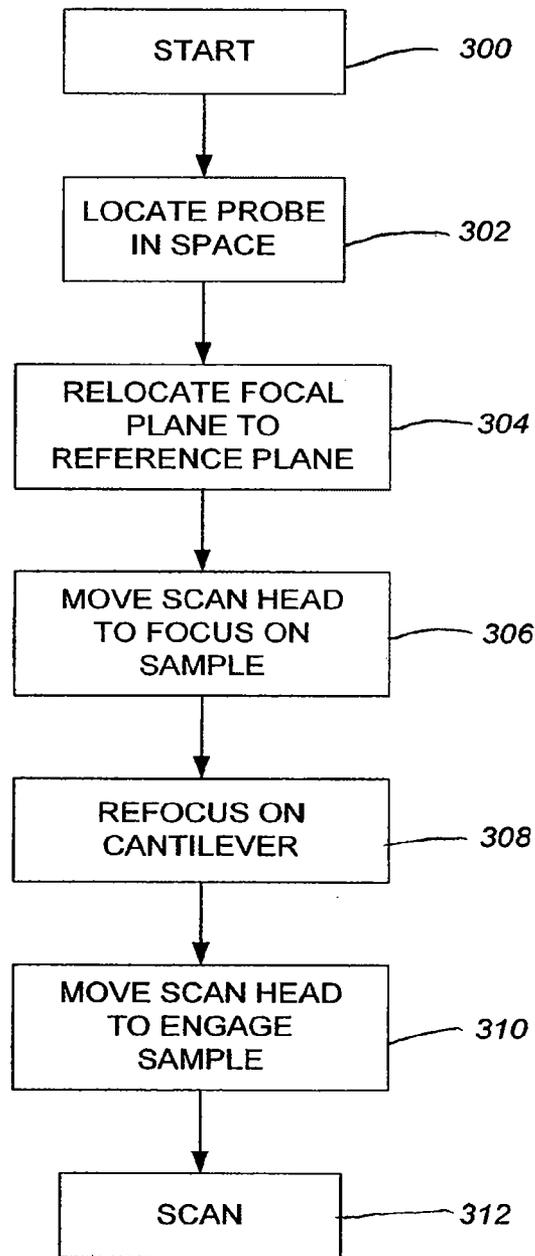


FIG. 10

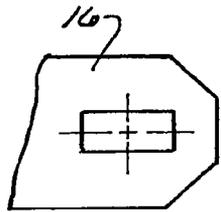


FIG. 11

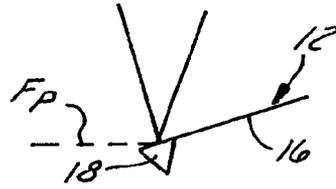


FIG. 12

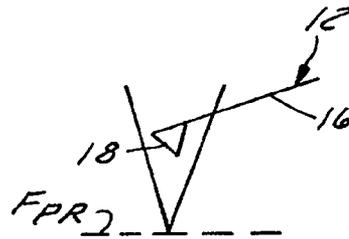


FIG. 13

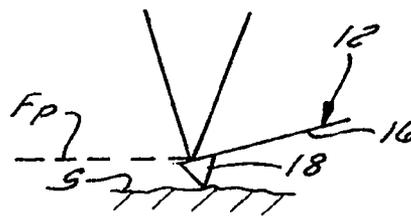
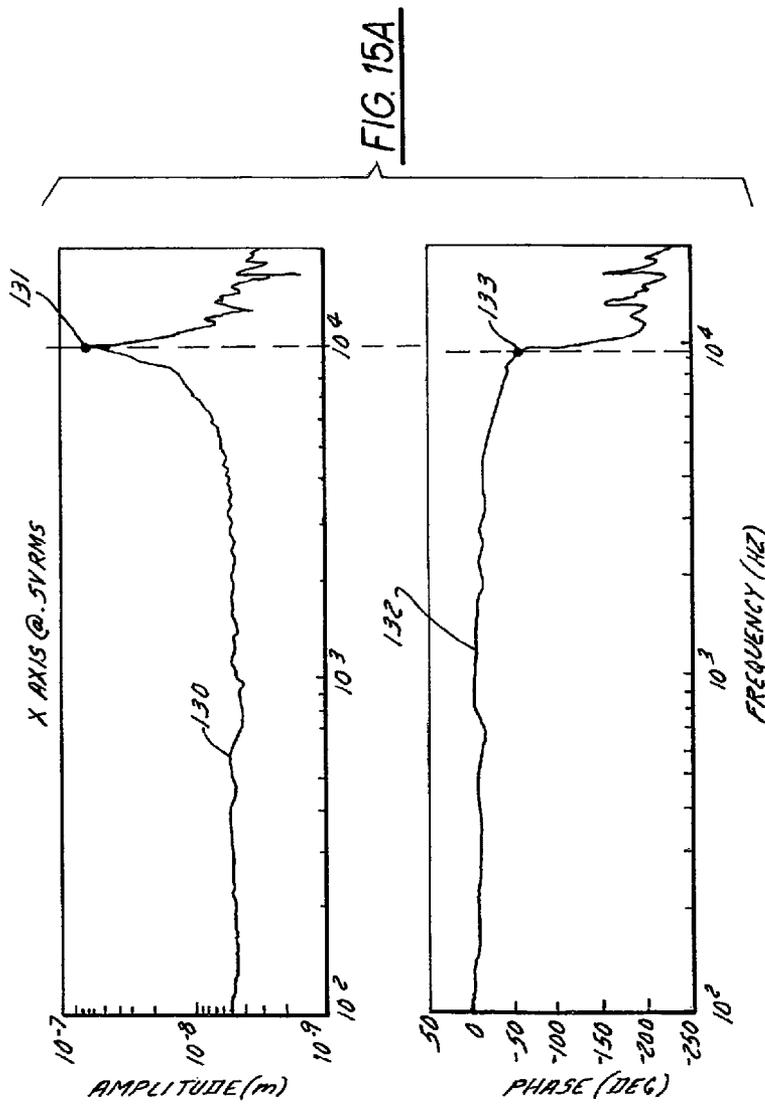
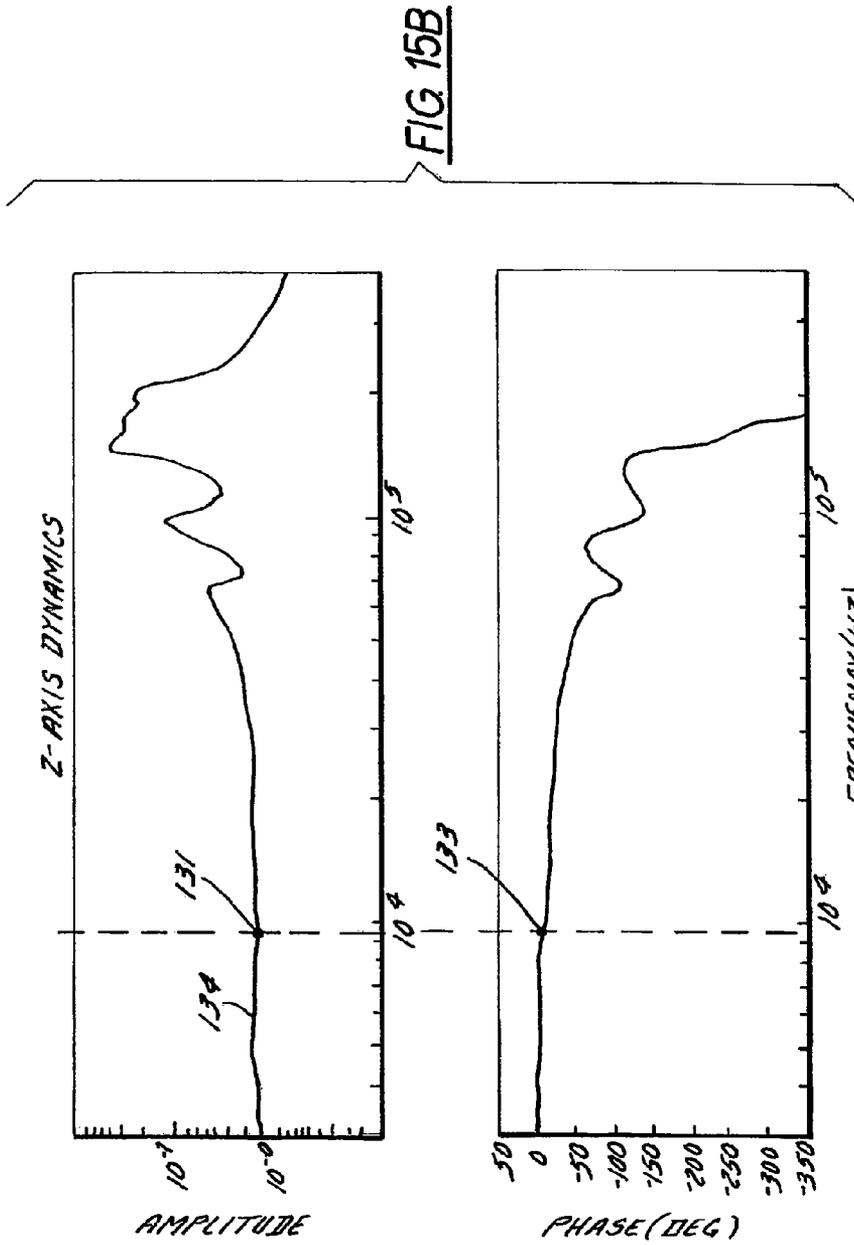


FIG. 14





FAST-SCANNING SPM SCANNER AND METHOD OF OPERATING SAME

CROSS REFERENCE TO A RELATED APPLICATION

This application is a continuation of co-pending and commonly assigned U.S. patent application Ser. No. 11/687,304, filed Mar. 16, 2007, the contents of which are hereby incorporated by reference in their entirety.

STATEMENT OF GOVERNMENT INTEREST

This invention was made with United States government support awarded by the following agency: NIST/ATP (Award #70NANB4H3055). The United States has certain rights in this invention.

BACKGROUND OF THE INVENTION

1. Field of the Invention

The present invention is directed to scanning probe microscopes (SPMs), and, more particularly, relates to a scanner for a SPM that can acquire high-quality images at high acquisition rates and to a method of operating such a scanner.

2. Description of Related Art

Scanning probe microscopes (SPMs), such as the atomic force microscope (AFM), are devices which typically use a tip and low forces to characterize the surface of a sample down to atomic dimensions. Generally, SPMs include a probe having a tip that is introduced to a surface of a sample to detect changes in the characteristics of a sample. By providing relative scanning movement between the tip and the sample, surface characteristic data can be acquired over a particular region of the sample and a corresponding map of the sample can be generated.

The atomic force microscope (AFM) is a very popular type of SPM. The probe of the typical AFM includes a very small cantilever which is fixed to a support at its base and which typically has a sharp probe tip attached to the opposite, free end. The probe tip is brought very near to or into contact with a surface of a sample to be examined, and the deflection of the cantilever in response to the probe tip's interaction with the sample is measured with an extremely sensitive deflection detector, often an optical lever system such as described in Hansma et al. U.S. Pat. No. RE 34,489, or some other deflection detector such as strain gauges, capacitance sensors, etc. The probe is scanned over a surface using a high resolution three-axis scanner acting on the sample support and/or the probe. The instrument is thus capable of creating relative motion between the probe and the sample while measuring the topography or some other surface property of the sample as described, e.g., in Hansma et al. U.S. Pat. No. RE 34,489; Elings et al. U.S. Pat. No. 5,266,801; and Elings et al. U.S. Pat. No. 5,412,980.

AFMs may be designed to operate in a variety of modes, including contact mode and oscillating mode. This is accomplished by moving either the sample or the probe assembly up and down relatively perpendicular to the surface of the sample in response to a deflection of the cantilever of the probe assembly as it is scanned across the surface. Scanning typically occurs in an "x-y" plane that is at least generally parallel to the surface of the sample, and the vertical movement occurs in the "z" direction that is perpendicular to the x-y plane. (Note that many samples have roughness, curvature and tilt that deviate from a flat plane, hence the use of the term "generally parallel.") In this way, the data associated with this

vertical motion can be stored and then used to construct an image of the sample surface corresponding to the sample characteristic being measured, e.g., surface topography. Similarly, in another preferred mode of AFM operation, known as TappingMode™ (TappingMode™ is a trademark owned by the present assignee), the tip is oscillated at or near a resonant frequency of the associated cantilever of the probe. A feedback loop attempts to keep the amplitude of this oscillation constant to minimize the "tracking force," i.e. the force resulting from tip/sample interaction. (Alternative feedback arrangements keep the phase or oscillation frequency constant.) As in contact mode, these feedback signals are then collected, stored and used as data to characterize the sample. Note that "SPM" and the acronyms for the specific types of SPMs may be used herein to refer to either the microscope apparatus or the associated technique, e.g., "atomic force microscopy."

Regardless of their mode of operation, AFMs can obtain resolution down to the atomic level on a wide variety of insulating or conductive surfaces in air, liquid or vacuum by using piezoelectric scanners, optical lever deflection detectors, and very small cantilevers fabricated using photolithographic techniques. Because of their resolution and versatility, AFMs are important measurement devices in many diverse fields ranging from semiconductor manufacturing to biological research.

As with most measuring devices, AFMs often require a trade off between resolution and acquisition speed. That is, some currently available AFMs can scan a simple surface with sub-angstrom resolution. These scanners are capable of scanning only relatively small sample areas, and even then, at only relatively low scan rates. Traditional commercial AFMs usually require a total scan time typically taking several minutes to cover an area of several microns at high resolution (e.g. 512×512 pixels) and low tracking force. The practical limit of AFM scan speed is a result of the maximum speed at which the AFM can be scanned while maintaining a tracking force that is low enough not to damage or cause minimal damage to the tip and/or sample. Professor Toshio Ando at Kanazawa University in Japan has made tremendous progress with high-speed AFM using an AFM that scans mm-sized samples over small distances, typically less than 2 μm. Professor Ando has achieved video scan rates with high resolution for this combination of small samples and small scan sizes.

Other systems, typically called "tip scanners," are known or have been proposed and/or implemented in which the probe is mounted on the scanner. One such system is incorporated in a line of instruments marketed by Veeco Instruments under the name Dimension®. That system employs a relatively massive tube scanner for the Z-actuator and has relatively low bandwidth. Another system is disclosed in Published U.S. Application Ser. No. 2006/00272398 to Hwang. In the system of the Hwang application, the probe is mounted on an actuator that, in turn, is mounted on an optical objective that focuses incoming laser light. The objective, in turn, is mounted on an x-y actuator. However, because the objective and other optics of the system are fixed relative to the probe, relatively large probes (having a width of at least of 20 μm, a length of more than 40 μm) are required to assure positioning of the focused laser beam on the cantilever. The typical probes used also have a resonant frequency F_o of roughly 400 kHz and a quality factor Q of around 400. The resulting response bandwidth for these probes is of the order of $F_o/Q \approx 1$ kHz. Due in part to its low-bandwidth probe, the resulting system has a maximum scan rate of less than 30 Hz (or 30 scan lines per second), and more typical imaging speeds are around 1 Hz.

On the other hand, SPMs that can acquire data rapidly can also suffer unacceptable tradeoffs. One such system is marketed by Infnitesima under the name Video AFM™. The Video AFM operates at video rates but with significant compromises to signal-to-noise ratio and resulting image quality. The Infnitesima system also operates in contact mode with force feedback that is not fast enough to respond to variations in sample corrugation within a scan line. In this system, the sample or the probe is mounted on a tuning fork. The probe is driven into contact with the sample while the sample or the probe is scanned by vibrating the tuning fork at or near its resonant frequency. Because the tuning forks need to be quite small (typically on the order of a few mm in size) to achieve high resonant frequencies, they are very sensitive to being loaded by extra mass. As a result, only very small (on the order of a few mm in size) samples or cantilever substrates can be mounted to the tuning fork without degrading the performance.

It is known to combine an AFM with a conventional optical microscope to provide a view of the surface features of the sample. Notably, high performance microscope objectives have a short working distance and must be positioned close to the sample surface. High resolution optical imaging is therefore difficult to implement in combination with traditional AFM detectors because there is insufficient space between the bottom of the objective and the probe to accommodate the geometry for the incoming and outgoing detection beams. Because of the weight of the optical microscope, it is difficult to incorporate the optics of an optical microscope into the scanner of the AFM without unacceptably reducing the instrument's scan rate.

Some optical microscope-equipped SPMs have attempted to overcome this limitation by directing laser light through the microscope objective. One such system has been commercialized by Surface Imaging Systems under the name ULTRAOBJECTIVE™ and is disclosed in international publication number WO 01/23 939. In the ULTRAOBJECTIVE™ system, a near field AFM probe, a z actuator assembly for the probe and optical focusing system are provided in a single housing in order to provide an interchangeable objective that can be inserted in the objective turret of an optical microscope. Its objective is fixed relative to the probe, and it lacks any mechanism for dynamically focusing the laser beam onto the probe.

Another drawback of conventional optical microscope equipped AFMs is that the optical microscope is provided only to allow the user to inspect the sample. It plays no role in focusing the laser beam on the cantilever. Hence, even if the system were provided for focusing the light spot on the cantilever, no mechanism would be available to provide the user with optical feedback during a focusing process.

The need therefore has arisen to provide a tip scanner for a SPM of a sufficiently high lowest fundamental lowest resonant frequency and sufficiently high resolution to make high resolution scans at high scan rates.

The need has additionally arisen to provide a SPM that can focus and target a sensing light beam on a probe, thereby permitting the use of relatively small focused beam spots and small probes in the SPM.

SUMMARY OF THE INVENTION

In accordance with a first aspect of the invention, a SPM with an integrated optical microscope is provided having a scan head that can acquire precise imaging data very rapidly. An objective is provided in the scan head to focus sensing and illumination light on the probe of the SPM. The SPM has a

relatively stiff, relatively light-weight scanner having a high fundamental resonant frequency. The objective preferably is vertically movable within the scan head to increase the focus range for a laser or other sensing light source, permitting the use of a relatively high cantilever with a commensurately high resonant frequency. The movable objective also permits illumination light to be focused on distinctly spaced objects, such as the probe and a sample surface located well beneath the probe. The objective is preferably also a "tracking objective" that moves with the scanner in the x-y plane to allow a sensing light beam's focused spot to remain focused on the probe during scanning. Optics are also preferably provided to permit panning of both the illumination beam of an integrated optical microscope and the sensing light beam as a unit. This panning permits the alignment or targeting of the focused sensing light beam on the cantilever under direct or indirect visual inspection of the focused illumination beam. This panning permits the use of an even smaller cantilever with a commensurately smaller resonant frequency.

In accordance with another aspect of the invention, an SPM is provided having a tip scanner including an objective that bears the tip. The tip scanner has a lowest fundamental resonant frequency greater than 2 kHz, preferably greater than 5 kHz, and even more preferably greater than 9 kHz. The objective is preferably a scanned objective that may or may not be moved by the actuator.

In accordance with another aspect of the invention, a SPM is provided having a tip scanner including an objective that bears the tip. The tip scanner has a fundamental resonant frequency greater than 500 Hz and a sensing light beam focused spot diameter of less than 10 μm. Preferably, the tip scanner has a fundamental resonant frequency greater than greater than 1 kHz and a sensing light beam focused spot diameter of less than 5 μm.

A SPM configured in accordance with the invention could be used to scan a wide variety of samples, including patterned wafers, biological samples, polymers, thin films, and data storage device component.

In accordance with still another aspect of the invention, a method is provided of scanning a sample with a SPM that includes obtaining images with a resolution of less than 1 Angstrom while scanning along lines of at least 4 μm at rates exceeding 50 Hz. These rates preferably exceed 100 Hz or 200 Hz, and even more preferably exceed 400 Hz.

These and other features and advantages of the invention will become apparent to those skilled in the art from the following detailed description and the accompanying drawings. It should be understood, however, that the detailed description and specific examples, while indicating preferred embodiments of the present invention, are given by way of illustration and not of limitation. Many changes and modifications may be made within the scope of the present invention without departing from the spirit thereof, and the invention includes all such modifications.

BRIEF DESCRIPTION OF THE DRAWINGS

Preferred exemplary embodiments of the invention are illustrated in the accompanying drawings in which like reference numerals represent like parts throughout, and in which:

FIG. 1 schematically illustrates an AFM with an integrated optical microscope constructed in accordance with a preferred embodiment of the invention;

FIG. 2 is a somewhat schematic perspective view of the optics of the instrument of FIG. 1;

FIG. 3A is a perspective view of a scan head of the instrument of FIG. 1;

FIG. 3B as a side elevation view of the scan head of FIG. 3A;

FIG. 4 is a sectional elevation view of the scan head of FIGS. 3A and 3B;

FIG. 5 is a perspective view of the operational elements of the scan head of FIGS. 3A and 3B;

FIG. 6 is a top plan view of a portion of the scan head of FIGS. 3A-4, including an x-y actuator, and objective, and an associated support structure;

FIG. 7A is a sectional elevation view of the objective of the scan of FIGS. 3A-4, showing the objective in a first operational position thereof;

FIG. 7B corresponds to FIG. 7A and shows the objective in a second operational position thereof;

FIG. 8 is a bottom plan view of the objective of FIGS. 7A and 7B;

FIG. 9 is a perspective view of a tip/tilt stage of the scan head of FIGS. 3A-4;

FIG. 10 is a flowchart illustrating a preferred technique for operating the AFM of FIG. 1;

FIG. 11 is a sketch showing the targeting of a sensing light beam on a cantilever of a probe during implementation of the process of FIG. 12;

FIGS. 12-14 are sketches illustrating a process for engaging a sample during implementation of the process of FIG. 10; and

FIGS. 15A and 15B are Bode plots illustrating the response of the scanner of FIGS. 1-9 in the x and z directions, respectively.

DETAILED DESCRIPTION OF THE PREFERRED EMBODIMENTS

As discussed in the "Summary" section above, the invention relates to a fast-acting scan head for a scanning probe microscope (SPM) such as an atomic force microscope (AFM). The scan head includes a probe, an actuator for the probe, and an optical objective that collectively form a scanner that moves as a unit for scanning. They are also arranged to permit the sample to be inspected at engagement using an illumination beam, and to place the focal point of the sensing light beam on the cantilever of the probe.

The objective may also be movable in the z direction to increase the range of focus of the objective. It also preferably comprises a targeting objective that moves with the scanner so as to remain focused on the cantilever during scanning. An AFM will now be disclosed having a scan head constructed in accordance with a preferred embodiment of the invention, it being understood that the scan head as disclosed can be used with a variety of other AFMs, other SPMs, and even other probe-based instruments. It should also be understood that a wide number of variations could be made to the disclosed scan head without departing from the spirit of the invention.

Turning to a FIG. 1, an AFM 10 is schematically illustrated incorporating a scan head 11 constructed in accordance with the present invention. The scan head 11 is mounted over a sample support 14 and bears a probe 12. An actuator (not shown) drives the scan head 11 and/or sample support 14 to move in at least the z direction, and preferably the x-y direction as well, as represented by the arrows 15 in FIG. 1. The probe 12 includes a cantilever 16 and a tip 18 mounted on the free end portion of the cantilever 16. The probe 12 may be coupled to an oscillating actuator or drive 20 that is used to drive probe 12 to oscillate, for instance, at or near the cantilever's resonant frequency. The oscillating drive 20 may be

coupled to an x-y actuator scanner 24 (described below) and probe 12 or may be formed integrally with the cantilever 16 of probe 12 as part of a self-actuated cantilever/probe. An electronic signal is applied from an AC signal source 21 under control of an AFM controller 22 to drive 20 to oscillate probe 12, preferably at a free oscillation amplitude A_o . The signal source 21 may be contained within the controller 22. Controller 22 typically consists of at least one computer and associated electronics and software that perform the tasks of data acquisition and control of the AFM. The controller 22 may consist of a single integrated analog and/or digital unit, or may consist of a distributed array of electronics and software. The controller 22 may use a typical desktop computer, a laptop computer, an industrial computer and/or one or more embedded processors. It will most likely be located off-board the scan head 11.

Probe 12 can also be actuated to move in the x and y directions relative to the sample support 14 using a suitable x-y actuator 24 mounted on the scan head 11. The preferred x-y actuator is described below. In the preferred embodiment, the moveable portions of the x-y actuator 24 and the elements that move with those portions during scanning form a "scanner." For purposes of this application, the term "tip scanner" means an assembly capable of scanning the probe 12 in a plane generally parallel to the sample (the x-y plane).

In the preferred embodiment, the scanner carries the probe 12, and additionally z-actuator 26, and objective 34. Note that the z-actuator can alternatively or additionally be configured to be separate from the scanner and move the sample instead. Probe 12 can also be actuated to move in the z direction using a z-actuator 26. The z-actuator preferably comprises a piezoelectric-stack, because the scanner is configured to scan the probe over the sample rather than vice versa, the scanner is commonly referred to as a "tip scanner." Alternatively, the scanner, or portions of it, may be employed to move sample support 14. For instance, the probe 12 may be mounted on a z-actuator that drives the probe to move in a vertical or z direction, and the sample support 14 may be mounted on a separate x-y actuator that drives the sample support 14 to move in the x-y plane.

The actuators for the x, y and z axes are preferably piezoelectric stacks. However, they can also employ any number of alternative actuation technologies, including but not limited to, other piezoelectric devices, actuators formed from electrostrictive, magnetostrictive, electrostatic, inductive, and/or voice coil drive mechanisms and other actuators that generate a motion in response to an input signal.

Probe 12 is preferably a microfabricated cantilever with an integrated tip. For optimal high speed performance, the preferred dimensions of the probes are of the order of 35 μm or less in length with resonant frequencies greater than 800 kHz, but many other dimensions including larger and smaller cantilevers can be used successfully. Probe 12, alternatively can be any of the wide field of probes that are used in scanning probe microscopy, including, but not limited to, probes for magnetic force microscopy, electric force microscopy, surface potential microscopy, chemical force microscopy, probes with carbon nanotube or carbon nanofibers, and probes for aperture-based or apertureless near-field scanning optical microscopy.

In operation, as the probe 12 is oscillated and brought into contact with a sample on the sample support 14, sample characteristics can be monitored by detecting changes in the oscillation of probe 12. In particular, a beam from a sensing beam light source 27 is directed by optics 28 in the scan head 11 towards the backside of probe 12 and is then reflected back to the optics and then directed towards a detector 30, such as

a four quadrant photodetector. The sensing light source 27 is typically a laser, preferably a visible or infrared laser diode. The sensing light beam can also be generated by other light sources, for example a He—Ne or other laser source, a superluminescent diode (SLD), a LED, an optical fiber, or any other light source that can be focused to a small spot. The term “laser” in the rest of this specification should be understood to cover a wide variety of these and other alternative light sources.

As the scanning light beam translates across the detector 30, appropriate signals are transmitted to controller 22, which processes the signals to determine changes in the oscillation of probe 12. Controller 22 typically generates control signals to actuate the z-actuator 26 under feedback to maintain a setpoint characteristic of the oscillation of probe 12. For example, controller 22 may be used to maintain the oscillation amplitude at a setpoint value, A_s , to insure a generally constant force between the tip and the sample. Alternatively, a setpoint phase or frequency may be used.

Still referring to FIG. 1, the scan head 11 also supports an optical microscope 32 permitting the optical inspection of the sample and also permitting focusing of the sensing light beam. It may be controlled, at least in part, by the controller 22. The microscope 32 includes a portion of the optics 28 as well as the objective 34. The optics 28 direct both the illumination beam and the sensing light beam to the probe 12 and direct the reflected sensing light beam to the detector 30 and the reflected illumination beam to a receiver 36. The objective 34 preferably may additionally be focused on a sample that is beyond the position of the cantilever. In this case the illumination beam is focused on the sample, and an image of the same is transmitted through the objective 34 and to the receiver 36. The receiver 36 may, for instance, be an imaging device such as a camera. The illustrated camera is positioned off-board the scan head 11 and serves both as a light source for the optical microscope 32 and as the imaging device. A CCD camera is a suitable imaging device. Alternatively or additionally, a separate light source and receiver could be provided on-board and/or off-board the scan head 11. In addition to or instead of a camera, the receiver 36 could be the human eye.

The illumination beam may be any form of light that can be observed either visually or with suitable instrumentation. It preferably comes from an ultra bright Light Emitting Diode (LED) but may also be an incandescent, fluorescent, or arc-based light source. It may be either monochromatic (e.g. a red LED) or a wider spectrum source approximating white light or even being white light

A workstation is also provided in the controller 22 and/or in a separate controller or system of connected or stand-alone controllers, that receives the collected data from the controller and manipulates the data obtained during scanning to perform the point selection, curve fitting, and distance determining operations. The workstation can store the resulting information in memory, use it for additional calculations, and/or display it on a suitable monitor, and/or transmit it to another computer or device by wire or wirelessly. The memory may comprise any computer readable storage medium, examples including but not limited to a hard disk, network storage, a flash drive, or a CD ROM.

The objective 34 is located in the optical path from the optics 28 to the probe 12. Preferably, it bears the z actuator 26 and the probe 12 so that all three devices move vertically as a unit. It also is preferably a scanned objective. That is, it is preferably coupled to the x-y actuator 24 so that the objective 34, z actuator 26, and probe 12 all move horizontally in the x-y plane under the power of the x-y actuator 24. In the

preferred embodiment, the objective 34 accomplishes two tasks: (1) focusing the sensing light beam onto the probe; and (2) providing an optical image of the probe and/or sample. In alternative embodiments, the objective can be arranged to accomplish only one of these tasks and/or additional tasks. In the preferred embodiment, the objective 34 focuses incoming sensing and illumination light on an object beneath the scan head 11, typically the cantilever and/or the sample. In addition, in conjunction with the optics 28, it directs outgoing illumination light to the receiver 36 and outgoing sensing light to the detector 30. The outgoing illumination light forms an image of the object. A portion of the objective 34 containing its optics can be driven to move in the z direction under power of a drive 38 in order to extend the focus range of the objective as discussed below.

The interaction between the optics 28 and the objective 34 will now be described with reference to FIG. 2.

As discussed briefly above in connection with FIG. 1, the optics 28 and objective 34 direct the incoming sensing light beam to the cantilever 16 and direct the outgoing sensing light beam to the detector 30. The illumination beam is also directed to and from the objective 34 by a mirror 220 located above the remainder of the optics 28. A collimating lens 50 and an aperture 52 are located upstream from the optics 28 in the direction of incoming sensing light beam transmission. The collimating lens 50 transforms incoming light into a beam of parallel rays. It could be formed integrally with or contained in the sensing light beam source 27. The aperture 52 shapes the focused light beam at the cantilever 16 plane so as to have a generally elliptical or rectangular shape having a relatively narrow width or “minor diameter” to minimize the spot size, and also to maximize optical lever sensitivity. The minor diameter refers to the measurement of the spot size across the direction of least extent. This permits use of a smaller cantilever as described in detail below. Similarly-shaped apertures, such as ovoid apertures, could also be used for this purpose. This does not mean that an aperture is mandatory to the system. An aperture could be eliminated entirely or replaced by a circular aperture, in which case the minor diameter would be the only diameter.

Still referring to FIG. 2, the optics 28 include a device that deflects the shaped sensing light beam downwardly from the aperture 52. A standard mirror would be suitable for this purpose if some other mechanism were provided for directing the illumination beam through the objective 34. However, in the preferred example is in which illumination beam enters the objective 34 directly from above, the device preferably is a filter 54 that is reflective of the wavelengths of sensing light beam (on the order of 690 nm or higher for a red laser diode) and that is transmissive of the wavelengths of the illumination beam, generally covering a wide range of the visible light spectrum. For an alternate preferred embodiment employing an infrared light source for the sensing beam, the cutoff wavelength for filter 54 would be correspondingly higher. A prism having two effective mirrors 58 and 60 is provided for directing outgoing sensing light to a mirror 62. The mirror 62 then deflects the reflected light upwardly to the detector 30.

Still referring to FIG. 2, in the preferred embodiment, the objective 34 is a dual lens achromatic objective. It includes first and second vertically spaced lens assemblies 64 and 66 that focus on incoming sensing light beam to a focal point which, ideally, is located on the back surface of the cantilever 16. Each of the lens assemblies 64 and 66 is formed from two lenses affixed to one another. This combination of four lenses reduces the aberration of the objective to the levels desired to both focus the sensing light beam onto the probe and provide a high quality color image of the sample from the illumination

beam. Lenses **64** and **66** are preferably achromatic doublets. Each lens preferably is customized to provide bright optical imaging and to provide a relatively broad wavelength spectrum.

The lenses of the preferred embodiment were custom designed using ZEMAX lens optimization software to minimize the optical path difference over the wavelengths of the illumination beam. In the preferred embodiment, the lens assembly has a working distance of greater than 8 mm and more preferably greater than 10 mm.

The objective **34** is also preferably relatively wide so as to provide a relatively large numerical aperture (NA) to accommodate significant cantilever bending—typically on the order of $\pm 4^\circ$. The preferred objective has an NA of more than about 0.28, preferably more than about 0.35, and most preferably of about 0.40. In the preferred embodiment, the light path for the illumination beam and the probe/sample imaging system is stepped down due to a numerical aperture of 0.28 to keep the aberrations at an acceptable level for the probe/sample image. A larger fraction of the objective is used to accommodate the reflected sensing light beam.

This combination of large numerical aperture and careful attention to minimizing aberrations produces the desired small laser spot diameter of less than 20 μm , preferably less than 10 μm , and most preferably of about 5 μm .

While the above description outlines the objective construction in the preferred embodiment, it is also possible to use a wide variety of different objective arrangements including more or fewer lenses. For a design that is optimized for maximum scan speed at the possible expense of image quality, it is possible to replace the four element objective with an objective with a single lens. Aspheric lenses, for example formed from lighter weight plastics, can achieve the combination of low aberration, wide NA, and low mass. Conventional stock lenses can also be used in a wide variety of configurations to form a suitable objective.

Referring now to FIGS. 3A, 3B, and 4, a preferred embodiment of the scan head **11** is shown less schematically. Scan head **11** includes an enclosed housing having upper and lower surfaces **70**, **72**, left and right surfaces **74**, **76**, and front and rear surfaces **78**, **80**. A first aperture **82** is formed in the front surface **72** for receiving a window **86** for the illumination light beam, and a second aperture is formed in the bottom surface **76** for receiving objective housing **88**. First and second knobs **90**, **92** extend from the right and front surfaces **76** and **78**, and third and fourth knobs **94** and **96** extend upward from the upper surface **70**. The first and second knobs **90** and **92** are threaded into a support **98** (FIG. 4) in the scan head **11** and engage a carriage **100** that bears the detector **30**. These knobs **90** and **92** can be manipulated to position the carriage **98** in the x-y plane to assure that the detector **30** is centered over the incoming sensing light beam. This permits the use of a smaller detector, potentially further increasing scan rate.

The objective **34** is preferably mounted in the scan head **11** so as to permit the objective **34** to be moved up and down relative to the probe to increase the range of focus of the objective, hence permitting the use of a smaller cantilever **16** and potentially further increasing scan rate. This vertical measurement also permits focusing of the illumination beam on an object beneath the cantilever **16**. This facilitates, for example, sample inspection in preparation for probe/sample engagement. It also is of relatively low mass so as to not significantly decrease the scanner's fundamental resonant frequency and, hence, maintain high scan rates. Toward this end, the lenses **64** and **66** that form the optics of the objective are mounted in the housing **88** or "barrel" as seen in FIG. 4 so as to be movable vertically relative to the barrel. The barrel **88**

is mounted on the x-y actuator **24**. A preferred arrangement for the mounting of the barrel on the x-ray-y actuator is shown in FIG. 6. Before describing the preferred arrangement in detail, it should be noted that an x-y actuator of the type described herein was developed by Dr. Paul Hansma and is assigned to The Regents of the University of California. It is described, e.g., in published U.S. Patent Application Ser. No. 2006/0112760, the subject matter of which is incorporated herein by reference.

The preferred arrangement includes a rigid mounting plate or scanner stage **110** fixed to the interior support of the scan head **11**. The rigid mounting plate **110** has a generally-cross-shaped aperture formed centrally therein that has two sets of orthogonally arranged x and y segments **112** and **114**. Two sets of x and y piezoelectric actuators **116** and **118** extend longitudinally along the centers of the respective segments **112**, **114**. One of the x-actuator sets **116** will now be described, it being understood that this description applies equally to the other x-actuator and the y-actuators **118** as well. One actuator of each set **116** has an outer end mounted on the end of the respective aperture segment **112** by a mount **120**, and an inner end supported on a central flexure **122** that spans the aperture segment **112**. The other actuator of each set **116** has an outer end connected to the central flexure **122** and an inner end connected to a second flexure **124** that also spans of the aperture segment **112**. The first or central flexure **122** of each set is not required but is beneficial because it increases the lowest resonant frequency of the associated piezoelectric actuator.

Actuators **116**, **118**, in combination with the flexures **122**, **124**, and **126**, provide an effective stiffness that, when loaded by the moving mass of the scanner, is designed to provide a fundamental resonant frequency of the scanner of at least 2 kHz, more preferably of at least 5 kHz, and even more preferably of more than 9 kHz. The significance of this feature will now be explained.

In scanning probe microscopes, feedback loops are used for multiple purposes. First, a feedback loop is used to attempt to maintain relatively constant value of average tip sample interaction by maintaining the cantilever deflection, amplitude, phase and/or frequency constant. This is often referred to as the z-feedback loop. The speed of the z-feedback loop is governed by the speed of the cantilever response, the z-actuator, and any associated electronics and amplifiers in the feedback loop. Another common form of feedback is position feedback. This type of feedback attempts to control the relative XY position of the scanner to compensate for thermal drift, and nonlinearities, hysteresis and/or creep in the actuator.

The fundamental resonant frequency F_0 of a scanner can limit the usable feedback bandwidth of the scanner. In general, the dynamic behavior of a mechanical system is determined by the fundamental resonant frequency. The fundamental resonant frequency is characterized by a sharp increase in phase lag and gain in the frequency response of a mechanical system. The addition of feedback control is used to modify the dynamic behavior by changing the gain and phase of a system as a function of frequency. For example, consider a simple feedback loop, for example a PI (proportional, integral) feedback loop common in probe microscopy. This type of control applies the sum of a constant gain (proportional) with that of 20 db/decade gain with 90 phase lag (integral gain). This feedback loop goes unstable as the gain is more than one at a phase shift of 180° . In this case, positive feedback occurs and the control loop becomes unstable. When a mechanical body goes through a simple resonance, 90 degrees of phase shift are accumulated at the resonant

peak, and there is generally an amplification of the actuator gain. (Real mechanical systems often have more complex phase behavior.) The controller gains are typically adjusted to roll off the overall system gain as the frequency approaches the actuator resonance. This strategy removes under-damped behavior in the control loop by minimizing the gain and reducing the phase lag near the fundamental resonant frequency. In practice, the feedback gains may be reduced even well below those at the limit of stability, to provide less overshoot in response to a step. In general, these steps will reduce the scanner system's usable bandwidth to a fraction of the fundamental resonant frequency. (Advanced control algorithms can mitigate the impact of these resonant frequencies.) For xy scan motion, the bandwidth of the scanner is typically limited by resonances of the xy scanner, and/or resonances in the z direction that couple to xy motion. For the z-axis, the feedback bandwidth may also be significantly limited by the cantilever response time, in addition or instead of the z-actuator resonance.

For the purposes of this application, the term "fundamental resonant frequency" is defined to be the lowest frequency at which there is a scanner resonance that has an impact on the usable bandwidth of a scanner. This definition of lowest fundamental resonant frequency specifically excludes those resonances that have no significant impact on the usable bandwidth of the scanner. These "minor resonances" may cause a variation in the system gain over a frequency range, but do not serve as a major limit for the feedback loop stability.

In a mechanical system, additional resonant behavior may exist in the frequency response at frequencies less than the fundamental resonant frequency. This resonant behavior does not affect the usable bandwidth if it is over-damped in nature due to a limited amount of associated phase lag and/or it is not of sufficient amplitude to be readily observed by the probe microscope electronics. The typical signature of a fundamental resonant frequency that does limit the bandwidth of a scanner is that there is a 90° or more phase shift at the resonance peak that is observed by the probe microscope system electronics. To be observed, a resonance must be one which generates an under-damped response of sufficient magnitude to be detectable by an actuator position sensor such as one of the sensors **128** discussed below and/or the detector **30** and their associated electronics. The reason for this caveat in the definition of fundamental resonant frequency is that it is possible to construct a tip scanner that has a component (for example, a cantilever spring clip) with a resonant frequency that is very low and yet does not affect the scanner performance.

By the definition above, the fundamental resonant frequency of the tip scanner assembly of the preferred embodiment is about 9.4 kHz. The lowest resonant mode is a vertical or z-axis "drumhead" mode where the objective oscillates up and down relative to the x-y plane of the scanner. The actual fundamental resonant frequencies of this system are shown by the transfer function elements or "Bode Plots" **130**, **132**, **134** and **136** of FIGS. **15A** and **15B**. FIG. **15A** illustrate the response in the x direction to driving the x actuators **116**. The response in the y direction to driving the y actuators **118** is essentially the same (not shown). The 9.4 kHz resonant frequency, denoted by the peak **131** amplitude curve **130** and the phase transition **133** in phase curve **132** in FIG. **15A**, is a result of the drumhead mode described above that gets excited by and coupled to x- or y-axis scanning motion. This frequency, however, does not get excited in the z direction by the z-actuator **26**, as shown in FIG. **15B**. No significant reso-

nance occurs at 9.4 kHz in the z-axis, as seen at points **131** and **133** in the z-axis amplitude and phase curves, **134** and **136** in FIG. **15B**.

To keep this resonance high, for a given scanner mass, the fundamental resonant frequency can be increased by making flexures **122** and **124** that are very stiff against vertical bending and torsional rotation. Flexures **126** are made extremely stiff against vertical bending. The net effect of these optimizations is to make the vertical stiffness of the tip scanner very high. In the preferred embodiment, the vertical stiffness of the tip scanner is designed to be about 10⁸ N/m. An approximation of the fundamental resonant frequency is given by:

$$F_o = \frac{1}{2 \cdot \pi} \cdot \sqrt{\frac{K_{scanner}}{M_{eff}}} \quad \text{Equation 1}$$

Where:

F_o = the fundamental resonant frequency of the scanner;
 $K_{scanner}$ = the stiffness of the scanner, and
 M_{eff} is the effective mass of the scanner, which is the mass of all objects that move with the scanner.

The effective mass of the scanner of this specific embodiment is about 35 grams. Using the formula above would predict a lowest frequency of the order of 8 kHz. In practice, the resonant frequency calculation is more complex for distributed mass and spring systems such as the described scanner. As such, the described scanner was designed and optimized using a combination of analytical calculations in Matlab computing software by The Math Works in combination with finite element analysis. Using finite element analysis and measurements of the tip scanner prototype, the inventors achieved lowest vertical resonant frequencies in excess of 9 kHz, when loaded with the objective.

The torsional and bending stiffness of the flexure elements depends on the length, height, and thickness of the flexure elements. These relationships are well-known or at least readily available to those skilled in the art. For instance, they are available from various engineering texts or by finite element analysis or by physical measurement. In general terms, it is desirable to make the length as short as practical and the height and thickness as large as practical. The practical limit to this optimization is when the bending stiffness in the desired direction of motion becomes so high that it resists the motion of the actuators.

In practice, the flexure elements **122**, **124** and **126** have been designed to be so stiff that they reduce the range of motion of actuators **116** and **118**, as shown in the equation below.

The maximum actuator displacement ΔX is given by:

$$\Delta X = X_o \cdot \left(\frac{K_{act}}{K_{act} + K_{flex}} \right) \quad \text{Equation 2}$$

Where:

X_o is the free range with no flexure,

K_{act} is the actuator stiffness, and

K_{flex} is the flexure stiffness. The price of using a high stiffnesses K_{flex} is a reduction of the available actuator range ΔX .

To achieve high resonant frequencies of the assembled scanner system, the flexures **122**, **124**, **126** are designed to have a stiffness in the direction of motion of 10-30% of the stiffness of actuators **116** and **118**. This allows an acceptable

13

trade-off of the scan range of the actuators to ensure that the combined system has a high lowest fundamental resonant frequency. In one embodiment, for example, a sacrifice of roughly 20% of the 22 μm range of the free actuator range achieves a stiffness sufficient for a resonant frequency of around 9.4 kHz while still achieving a scan size of 18 μm .

In a preferred embodiment, the actuators **116** and **118** are combinations of sets of two 5 mm \times 5 mm \times 13.5 mm piezo stacks and two 5 mm \times 5 mm \times 9 mm stacks, respectively. The combined stiffness of the actuator sets roughly 5×10^7 N/m in both the x and y directions. The total flexure stiffness was chosen to be around 1×10^7 N/m, or 20% of the actuator stiffness. This large bending stiffness of the flexures also gives a slight increase ($\sim 10\%$) over the actuator stiffness.

Additionally, the flexure materials and thicknesses have been chosen to ensure that the maximum stress in the flexures is well below yield stresses for those materials. In one embodiment, the scanner stage **110** is constructed from a 7076-T6 aluminum alloy, and design stresses were kept below 10 kpsi, or under 14% of the yield stress. Alternative embodiments could also be constructed from invar (for superior thermal expansion performance) or titanium, for example.

It can be seen that the second or innermost flexures **124** form a generally square frame. The barrel **88** is mounted to this frame by four sets of flexures **126**, each of which extends perpendicularly from a respective portion of the barrel **88** to respective one of the innermost flexures **124**. Due to the arrangement of the piezoelectric elements **116**, **118** and the flexures **122**, **124**, and **126**, actuation of the x or y actuator **116** or **118** drives the barrel **88** to move in the x or y direction within the x-y plane with virtually no movement in the other direction within that plane or in the z direction.

Referring to FIGS. 6, 7A and 7B, the scanner may optionally be outfitted with position sensors **128** for the x-y actuator **24** and/or the z-actuator **26** to provide feedback for maintaining actuator linearity and/or compensate for creep and drift. Capacitance, optical, strain gauge, or inductance sensors or any other sensor that produces an output indicative of actuator movement and/or position could be used. Any sensor that contacts the actuator should have minimal mass. For instance, small strain gauges **128** may be mounted on the z-actuator **26** in a Wheatstone bridge configuration. Similar strain gauges **128** may be mounted on the x and y piezoelectric elements **116** and **118** or, on the frame formed by the flexures **126**.

Turning now to FIGS. 7A and 7B, the objective **34** includes the barrel **88**, a lens support **140**, and a sleeve **142** located radially between the lens support **140** and the barrel **88**. A gear **144** is rotatably mounted on the outer surface of the upper end of the barrel **88**. It is restrained from radial motion relative to the barrel **88** by an o-ring **146**. The barrel **88**, sleeve **142**, and lens support **140** will now be described in turn.

The barrel **88** is a relatively rigid, preferably metal, structure affixed to the x-y actuator **24** as described above. It takes the form of a hollow cylinder that is open at its top end **150** and is enclosed at its bottom end **152**. It is also stepped at its bottom end. A central aperture **154**, covered by a transparent window **156**, is formed in the bottom end **152** to permit light to pass between the objective **34** and the probe **12**. The aperture **154** is also counter-bored at its bottommost end to form a mounting location **158** for the z actuator **26** and the probe **12**. A socket **159** is formed in the outer wall near the bottom end of the barrel **88**, and a vent passage **161** is located beneath the socket **159**.

The sleeve **142** comprises an annular metal ring located in a recess **160** in the outer periphery of the lens support **140**. The sleeve **142** is retained in the recess **160** by a ring **162** at its

14

upper end and by the bottom of the recess **160** at its lower end. This mounting prohibits the sleeve **142** from moving axially relative to the lens support **140** but permits free rotational movement there between. An annular shoulder **164** extends radially from the upper end of the sleeve **142** and is affixed to the gear **144** so that the gear **144** and sleeve **142** rotate as a unit. The outer periphery of the sleeve **142** beneath the shoulder **162** is threaded at **166** and mates with an internally threaded portion **168** of the inner surface of the barrel **88**. The mating threads cause the sleeve **142** to screw into and out of the barrel **88** upon rotation of the gear **144** and sleeve **142**.

The lens support **140** comprises a cylindrical tube having a maximum OD that closely matches the minimum ID of the barrel **88** so as to permit sliding movement of the lens support **140** within the barrel **88** with minimum "play" or side-to-side motion therebetween. The lower end of the lens support **140** is stepped to match the step in the barrel **88**. First and second O-rings **180**, **182** are mounted in the OD of the lens support **140** at its bottom and central portions, respectively, so as to virtually eliminate play between the lens support **140** and the barrel **88**. The inner peripheral surface of the lens support **140** is stepped at two locations **184** and **186** to provide mounting locations for the first and second lens assemblies **64** and **66**, described above. A ball **188**, mounted in the socket **159**, engages a groove **189** formed in the outer surface of the lens support **140** so as to prevent rotational movement of the lens support **140** relative to the barrel **88** while permitting longitudinal vertical movement therebetween. A flag **190** is mounted on the upper surface of the lens support **140** for engagement with a limit switch or a similar mechanical, electrical, or optical sensor when the lens support **140** reaches its uppermost or lowest limit of travel.

A bottom chamber **192** is formed between the bottom of the lens support **140** and the inner surface of the bottom portion of the barrel **88**, and an annular chamber **194** is formed between the lower portion of the outer periphery of the lens support **140** and the inner periphery of the barrel **88** at a location above the step in the barrel. Another annular chamber **196** is formed between the ID of the gear **144** and the OD of the sleeve **142** above the upper end of the barrel **88**. All three chambers **192**, **194**, and **196** increase in size as the lens support **140** moves upwardly within the barrel **88** and decrease in size as the lens support **140** moves downwardly within the barrel **88**. Preferably, measures are taken to vent air from the chambers **192**, **194**, and **196** during downward movement of the lens support **140**. In the current embodiment, air from the bottom chamber **192** can vent into the annular chamber **194** by flowing past the O-ring **180**, and air from both chambers **192** and **194** can be vented from the barrel **88** by passing through the vent passage **161**. Air from the upper chamber **196** is vented by flowing between the gear **144** the outer surface of the barrel **88** and past the O-ring **146**.

In use, when the gear **144** is driven to rotate by the drive **38** in FIG. 1, the sleeve **142** is driven to rotate relative to both the lens support **140** and the barrel **88**. This rotation causes the sleeve **142** to screw into or out of the barrel **88**, driving the lens support **140** to move upwardly or downwardly relative to the barrel **88**. The ball **188** prevents the lens support **140** from rotating. Air trapped in the chambers **192**, **194**, and **196** during downward movement of the lens support **140** vents as described above. The range of motion that is available may vary with operator preference and system requirements. Ideally, it should be long enough to focus on the cantilever and to also focus on the sample for inspection purposes when the probe **12** is located well above the sample surface. This requires a focus depth of on the order of 1 mm. In the illustrated embodiment, this focus depth is achieved by providing

15

the lens support **140** with a stroke of at least 1 mm, preferably of 2 mm or more, and most preferably about 3 mm, with respect to the barrel **88**.

Referring now to FIG. **8**, the probe **12** and z-actuator **26** are mounted on the bottom of the barrel **88** by a flexure **200** extending across the mounting location **158**. This flexure **200** prevents any movement of the z-actuator **26** in the x-y plane during operation of the z-actuator **26**.

The drive **38** of FIG. **1** may comprise any device, assembly, or system that can be used to drive the gear **144** to rotate through a precisely controllable angular range of motion. It is also preferably one that does not in any way constrain the lens support **140** from vertical motion or that interferes with the operation or reduces the range of operation of the x-y actuator **24**. A manually operated knob could be used for this purpose. A powered motor is preferred. Referring to FIGS. **4** and **5**, the presently-preferred drive comprises a stepper motor **210** mounted in the scan head **11**. The stepper motor **210** has an output gear **212** coupled to the drive gear **144** for the objective by an idler gear **214**. In the preferred embodiment, the stepper motor, gear train, and thread pitch are selected to achieve a precision of less than 1 μm of lens support vertical motion per motor step. The idler gear **214** and drive gear **144** have more than ample backlash to permit the range of motion provided by operation of the x-y actuator **24** and, accordingly, impose no constraints on operation of the x-y actuator **24**.

In use, the sensing light beam emitted by the light source **26** is collimated by the collimator **50**, shaped by the aperture **52**, and then deflected to the objective **34** by the filter **54** as seen in FIG. **2**. The light is then focused onto the cantilever **16** by the objective **34** and is reflected back through the objective **34** to the filter **54**. However, because the outgoing sensing light beam is traveling along a subtly different path than the incoming light beam due to the effect of its deflection from the inclined cantilever **16**, the outgoing beam impinges on the first prism surface **58** after being deflected by the filter **54** rather than being directed back toward the aperture **52**. It is then deflected to the receiver **30** by the second prism surface **60** and the mirror **62**. The resultant data, or information derived from it, may be viewed, stored, and/or transmitted to a different location.

At the same time, the illumination beam from the camera **36** enters through the front window **86**, is deflected off the upper mirror **220**, and travels to the objective **34**, which focuses the illumination beam onto an object, typically either the cantilever **16** or the underlying sample surface. The reflected light illumination beam thereafter returns through the objective **30** and is deflected again by the mirror **220** so that it is directed back to the camera **36**. The optical image, or information derived from it, may be viewed, stored, and/or transmitted to a different location.

The illumination beam mirror **220**, as well as the optics including the filter **54** and the prism, are preferably movable as a unit in order to pan the instrument in the x-y plane. Because it adjusts both the sensing light beam optics and the illumination beam optics, this adjustment permits the sensing light beam focal point to be centered or "targeted" on the cantilever **16** and to be at the center of the optical microscope's field of view. The ability to both target and focus the sensing light beam permits the use of a smaller cantilever, potentially further increasing scan rates.

In a preferred embodiment, this targeting is made possible by mounting the optics **28** and mirror **220** on a "tip-tilt" stage **230** seen in FIGS. **4** and **9**. The tip-tilt stage **230** includes a gimbal **232** in the center of a plate **234**. As best seen in FIG. **4**, the gimbal **232** is formed from an annular, generally spherical surface **236** that bears against a mating socket **238** formed

16

in a support beam **240** in the scan head **11**. Referring simultaneously to FIGS. **3A**, **4**, and **9**, first and second vertical posts **242**, **244** extend vertically from the top surface of the plate **234**, through the beam **240**, and out of the top surface **70** of the scan head **11**. Knobs **94** and **96** are mounted on the upper ends of the posts **242** and **244**. The posts **242** and **244** are threaded into bushings **246** and **248** mounted in the beam **240** as seen in FIG. **9**. Rotation of either of the knobs **94** or **96** screws the associated post **242** or **244** into or out of the beam **240**, hence driving an associated corner of the plate **234** upwardly or downwardly. This motion results in rotation of gimbal **232** and tilting of the tip-tilt stage **230**. The posts **242** and **244** are positioned such that vertical motion of the first post **242** rotates the gimbal in the y-z plane for y panning and vertical motion the second post **244** rotates the gimbal in the x-z plane for x panning.

As mentioned above, this panning permits the sensing light beam to be precisely centered on the cantilever **16**, preferably under visual inspection with the aid of cross-hairs or the like on a lens or monitor as seen in FIG. **11**. When combined with the focusing effect of movable objective **34**, a sensing light beam spot having a minor diameter of less than 20 μm can be centered on the cantilever **16**. That sensing light beam spot minor diameter is preferably less than 10 μm , and most preferably less than 5 μm . Spot diameters are defined to be the width at which the amplitude of light drops to $1/e^2$ of the amplitude at the center of the spot. Provision of this small sensing light beam spot permits the use of a correspondingly small, correspondingly high resonant frequency cantilever. Cantilevers having a width of 10 μm or less and a length of 35 μm or less have a resonance frequency more than 500 KHz. This high-bandwidth cantilever, in conjunction with the use of the high-bandwidth x-y actuator assembly **24**, permits faster scans than would be possible with larger cantilevers and high-mass scanners. In fact, the fundamental resonant frequency of the scanner is greater than 2 kHz, preferably greater than 5 kHz, and even more preferably greater than 9 kHz.

The operation of the instrument **10** is thus far describe will now be explained in conjunction with the flowchart of FIG. **10**.

The process of FIG. **10** proceeds from START in Block **300**, to Block **302**, where the operator locates the probe in space and centers to the sensing light beam on the cantilever **16**. This will typically involve a combination of panning in x and y under visual inspection by manipulating the knobs **94** and **96** to center the sensing light beam on the cantilever **16** under visual inspection of the camera **36**, which pans with the sensing light beam. It also will typically involve operating the drive **38** to focus the sensing light beam on the cantilever **16**. The illumination beam will simultaneously focus on the cantilever **16** at this time, providing visual confirmation of sensing light beam centering and focusing. This focusing is shown schematically in FIG. **12**.

Next, in Block **304**, the drive **38** is engaged to move the focal plane of the objective **34** to a specified, preferably fixed, "reference" distance below the cantilever **16**, thus positioning the focal plane in a reference plane F_{PR} as shown schematically in FIG. **13**. The reference distance will ultimately be the initial tip/sample spacing at the start of the sample engagement process. It should be large enough to provide tolerance during sample engagement, i.e., to assure that the tip does not "crash" into the sample when it is being moved toward it. It should not be so large, however, that the obscuration of the cantilever substrate makes it difficult to view an object in the focal plane. A distance of about 1 mm is preferred. Then, in Block **306**, the scan head **11** is driven downwardly under visual inspection of the optical microscope until the sample

comes into focus, providing the operator with knowledge that the probe 12 is at the reference distance away from the sample surface. The process then operates the drive 38 to refocus the focal plane on the cantilever 14 as denoted by Block 308, and the scan head 11 is then moved downwardly the reference distance in Block 310 to bring the tip 18 into operative interaction with the sample. As seen in FIG. 14, both the sample surface and the cantilever will be in or very near the focal plane of both the sensing light beam and the illumination light beam at this time. If necessary or desired, the knob(s) 92 and/or 94 can be actuated to center the reflected sensing light beam on the detector 30.

Finally, in Block 312, a scan can then be performed in any desired fashion. The x-y actuator 24 may, for instance, be controlled to move the probe 12 in a raster scan. The objective 34 moves with the x-y scanner at this time and, accordingly, "tracks" movement of the probe 12. The amplitude or phase of probe oscillation is kept constant during scanning using feedback signals to control the z-actuator 26, which are generated in response to tip-sample interaction. These feedback signals are then collected, stored and/or used as data to characterize the sample. The resulting information, and/or information acquired by combining this data with other data, can be stored, transmitted to another device, and/or displayed in a suitable monitor.

Because of the small mass of the tip scanner and the high bandwidth, small probe 12, the scan can be performed very rapidly while still obtaining high-resolution images. In fact, sample features on the order of 0.5 Angstrom can be resolved while scanning along lines of 4, 5 or 10 μm or even longer at rates exceeding 50 Hz, preferably exceeding 100 Hz or 200 Hz, and even more preferably exceeding 400 Hz. These scan rates can be achieved at a force control bandwidth, i.e., a bandwidth of the force control feedback used to control the z actuator, of at least 5 kHz, and even of 10 kHz to 15 kHz or more in TappingMode operation and 30 kHz or more in contact mode operation. A sample having an RMS roughness of at least 5 μm can be scanned along scan lines of at least 4 μm with an average tracking score of at least 80% at the rates discussed above. In addition, because the tip is scanned rather than the sample, sample size is not limited. Samples having a largest dimension of more than 7 mm, more than 10 mm and even more than 100 mm can be scanned.

The process as discussed herein as well as other processes falling within the scope of the present invention could be used to scan a wide variety of samples, including but not limited to, a patterned wafer such as a semiconductor wafer, a thin film, a polymer, a biological sample, or a data storage component. Examples of data storage components include a hard disk head, a media surface, a rowbar, a slider, and a head wafer.

Other features and advantages of the invention will become apparent to those skilled in the art from the following claims.

The invention claimed is:

1. A scanning probe microscope (SPM) tip scanner comprising:

- a support;
- a scanner that is mounted on the support, the scanner including
 - a probe,
 - an objective that outputs a sensing light beam that impinges on the probe, wherein the objective includes a lens that is movable vertically relative to the probe to adjust a focal point of a transmitted light beam relative to the probe,
 - flexures that couple the scanner to the support,
 - an xy actuator that drives the scanner to move relative to the support in least an x-y plane, and

a z actuator that is supported on the objective and that moves the probe in a z direction that is perpendicular to the x-y plane

wherein the scanner has a fundamental resonant frequency greater than 2 kHz.

2. The tip scanner of claim 1, wherein the scanner has a fundamental resonant frequency of greater than 5 kHz.

3. The tip scanner of claim 1, further comprising a detector that receives a light beam that is reflected from the probe, the detector being located off-board the scanner.

4. The tip scanner of claim 1, further comprising an objective housing on which the probe is supported and within which the lens of the objective is vertically movable.

5. The tip scanner of claim 1, wherein the tip scanner moves the probe in the x-y plane at a rate of at least 30 Hz and has a sensing light beam spot minor diameter of less than 10 microns, and wherein the probe has fundamental resonant frequency greater than 500 Hz.

6. A scanning probe microscope (SPM) tip scanner comprising:

- a support;
- a scanner that is mounted on the support, the scanner including
 - a probe,
 - a scanned objective that outputs a sensing light beam that impinges on the probe,
 - flexures that couple the scanner to the support,
 - an xy actuator that drives the scanner to move relative to the support in least an x-y plane, and
 - a z actuator that is supported on the scanned objective and that moves the probe in a z direction that is perpendicular to the x-y plane; and
- wherein the scanner has a fundamental resonant frequency greater than 2 kHz.

7. The SPM of claim 6, wherein the objective includes a lens that is movable vertically relative to the probe to adjust a focal point of a transmitted light beam relative to the probe.

8. The SPM of claim 6, further comprising a detector that receives a light beam that is reflected from the probe, the detector being located off-board the scanner.

9. The SPM of claim 6, further comprising an electrically powered drive that is selectively operable to drive the objective lens to move vertically relative to the probe, the drive being located off-board the scanner.

10. The SPM tip scanner of claim 6, wherein the tip scanner moves the probe in the x-y plane at a rate of at least 30 Hz and has a sensing light beam spot minor diameter of less than 10 microns, and wherein the probe has fundamental resonant frequency greater than 500 Hz.

11. A scanning probe microscope (SPM) tip scanner comprising:

- a support;
- a tip scanner including
 - a probe,
 - a scanned objective, wherein the scanned objective includes a lens that is movable vertically relative to the probe in order to adjust a focal point of a transmitted light beam relative to the probe,
 - flexures that couple the tip scanner to the support,
 - an xy actuator that drives the tip scanner to move relative to the support in least an x-y plane,
 - a z actuator that is supported on the scanned objective and that moves the probe in a z direction that is perpendicular to the x-y plane; and
- wherein the probe has a fundamental resonant frequency greater than 500 Hz and the tip scanner has a sensing light beam spot minor diameter of less than 10 microns.

19

12. The SPM of claim 11, wherein the tip scanner moves the probe in the x-y plane at a rate of at least 30 Hz and the tip scanner has a fundamental resonant frequency of at least 2 kHz.

13. The SPM of claim 11, further comprising an electrically powered drive that is selectively operable to drive the objective lens to move vertically relative to the probe, the drive being located off-board the scanner.

14. The SPM of claim 13, wherein the drive has backlash therein that permits movement of the scanner in the x-y plane without interference from the drive.

15. The SPM of claim 11, further comprising optics that direct the light beam to and from the objective, at least some of the optics being located off-board the scanner.

16. The SPM of claim 15, wherein some of the optics direct an illumination light beam and a sensing light beam to and from the probe and are movable to pan the light passing therethrough so as to direct the sensing light beam onto a desired portion of the probe.

17. The SPM of claim 15, wherein some of the optics are mounted on a tip/tilt stage that is movable in x, y, and z planes.

18. A scanning probe microscope (SPM) comprising:

a support structure;

a sample support capable of supporting a sample having a largest dimension of at least 7 mm; and

20

a tip scanner including

a probe,

a scanned objective,

flexures that couple the tip scanner to the support structure,

an xy actuator that drives the tip scanner to move relative to the support structure and the sample support in least an x-y plane at a rate of at least 30 Hz, and

a z actuator that is supported on the scanned objective and that moves the probe in a z direction that is perpendicular to the x-y plane.

19. The SPM of claim 18, wherein the tip scanner has a fundamental resonant frequency greater than 2 kHz and a sensing light beam spot minor diameter of less than 10 microns, and wherein the probe has a fundamental resonant frequency of greater than 500 Hz.

20. The SPM of claim 18, further comprising a detector that receives a light beam that is reflected from the probe, the detector being located off-board the scanner.

21. The SPM of claim 18, further comprising an electrically powered drive that is selectively operable to drive the objective lens to move vertically relative to the probe, the drive being located off-board the scanner.

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